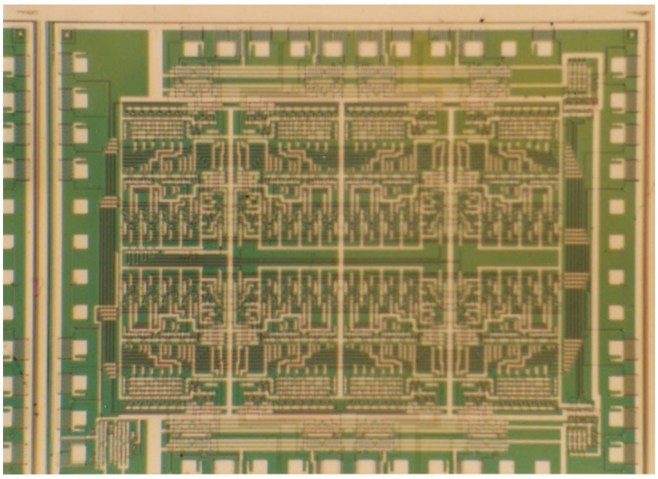
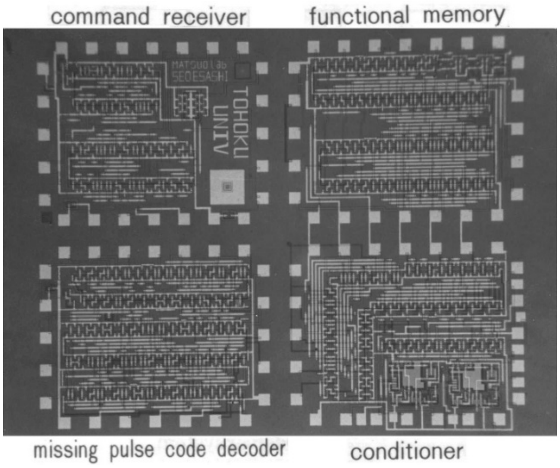
8 Fabricated custom IC (1) (channel length 10 μm)



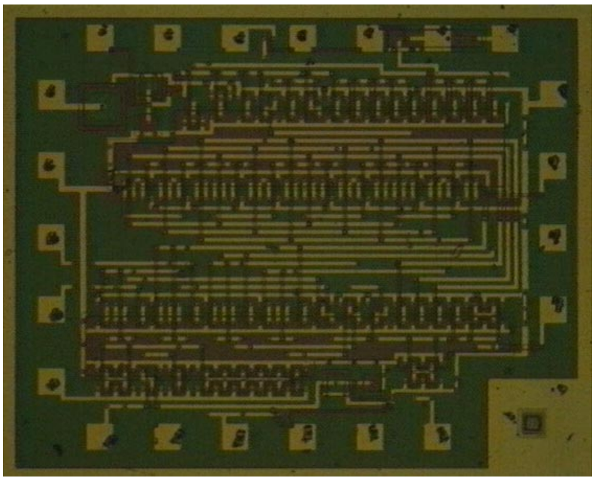
Bit serial parallel image processing IC

(M. Esashi : Basics of integrated circuit design, (1986) Baifukan) (in Japanese)



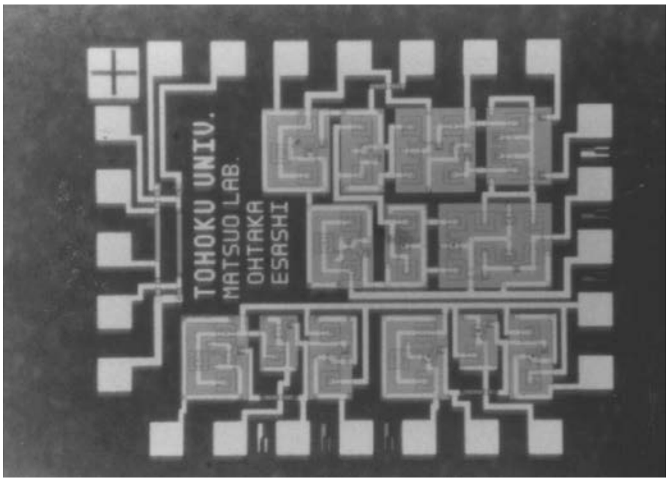
Implantable telemetry IC

(H.Seo, M.Esashi and T.Matsuo : Manufacture of Custom CMOS LSI for an Implantable Multipurpose Biotelemetry System, Frontiers of Medical and Biological Engineering, 1, 4 (1989) 319-329)



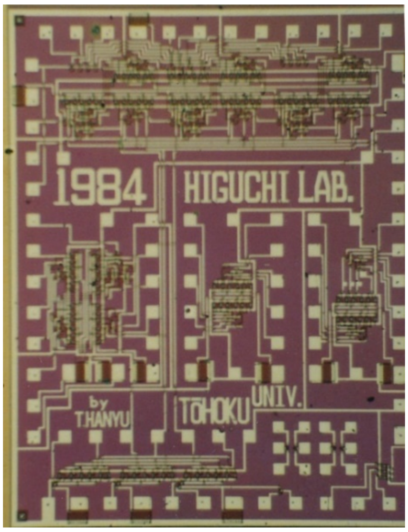
IC for tactile sensor array using common two wires

(M.Esashi and Y.Matsumoto : Common Two Lead Wires Sensing Transducers'91, San Francisco, USA (1991) 330-333)



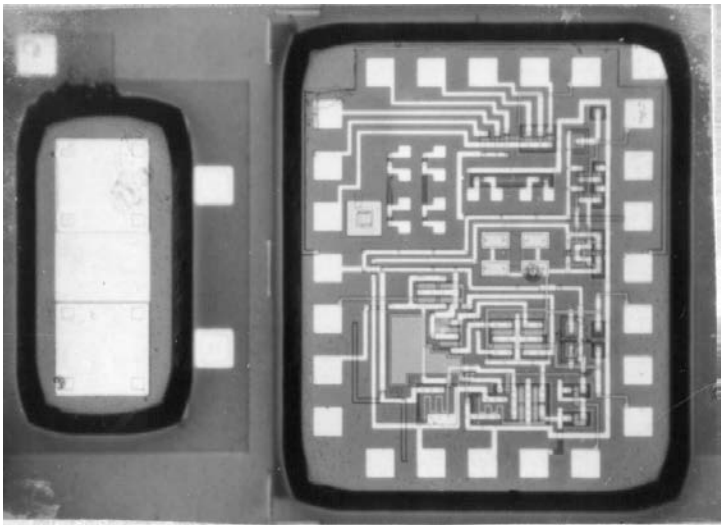
SOS (Si on Sapphire) CMOS OP amp IC for high temperature

(M. Esashi, S. Ohtaka, T.Matsuo : Fabrication of High Temperature Integrated System, Circuit and High Temperature Pressure Sensor, Technical Report IECE, SSD86-57 (1986) 67-74) (in Japanese)



Multi-valued logic IC

(M.Kameyama, T.Haniyu, M.Esashi and T.Higuchi : An NMOS Pipelined Image Processor Using Quaternary Logic, IEEE Int. Solid-State Circuit Conf., San Francisco, USA (1985) 86-87)



Direct bonded capacitive pressure sensor using switched capacitor IC

(S.Shoji, T.Nisase, M.Esashi and T.Matsuo : Fabrication of an Implantable Capacitive Type Pressure Sensor, The 4th Int. Conf. on Solid State Sensors and Actuators, Tokyo, Japan (1987) 305-308)